

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Gabric, <i>et al.</i>	Docket No:	2006 VJ 33543 US
Filed:	Herewith	Art Unit:	TBD
Serial No.:	Not Assigned	Examiner:	TBD
For:	Plasma Excited Chemical Vapor Deposition Method, Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly		

Mail Stop PCT
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Dear Sir:

Applicant respectfully requests entry of this preliminary amendment prior to Examiner's examination of the application.